

AMORPHOUS DIFFUSION BARRIERS

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Amorphous W-Zr Barrier

MOTIVATION

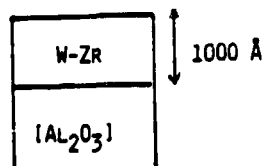
(PREVIOUS STUDIES: Ni-W, Ni-Mo, Cu-Ta)

- SUBSTITUTE NI WITH ZR TO AVOID INTERFACIAL PENETRATION OF NI INTO SI SUBSTRATE AT LOW TEMPERATURES ($\sim 400^{\circ}\text{C}$)

NOTE:

- I) NI REACTS WITH SI AT $\sim 200^{\circ}\text{C}$
- II) NI IS THE MOVING SPECIES IN NI+SI REACTION
- III) ZR REACTS WITH SI AT $\sim 700^{\circ}\text{C}$
- IV) SI IS MOVING SPECIES IN ZR+SI REACTION

Crystallization

ANNEALED $500-900^{\circ}\text{C}$ (30')

X-RAY

 $T_c \sim 900^{\circ}\text{C}$

PROCESSING

Experimental

RF SPUTTER DEPOSIT W-Zr FILMS FROM A W TARGET
COVERED WITH Zr STRIPES IN 10mTorr Ar
(BASE PRESURE < 1E-6 Torr)

2 COMPOSITIONS: $W_{70}Zr_{30}$

$W_{40}Zr_{60}$

DEPOSITION RATE: $\sim 400 \text{ \AA} / \text{MIN}$

PL DEPOSITION WITHOUT BREAKING VACUUM $\sim 120 \text{ \AA} / \text{MIN}$

ANNEALING IN VACUUM: PRESSURE < 5E-7 Torr

ANALYSIS:

XPS (ATOMIC DEPTH PROFILES)

SEM, EDAX (SURFACE MORPHOLOGIES)

X-RAY (PHASE IDENTIFICATION)

N⁺P Shallow Junctions

JUNCTION DEPTH : 0.35 μm

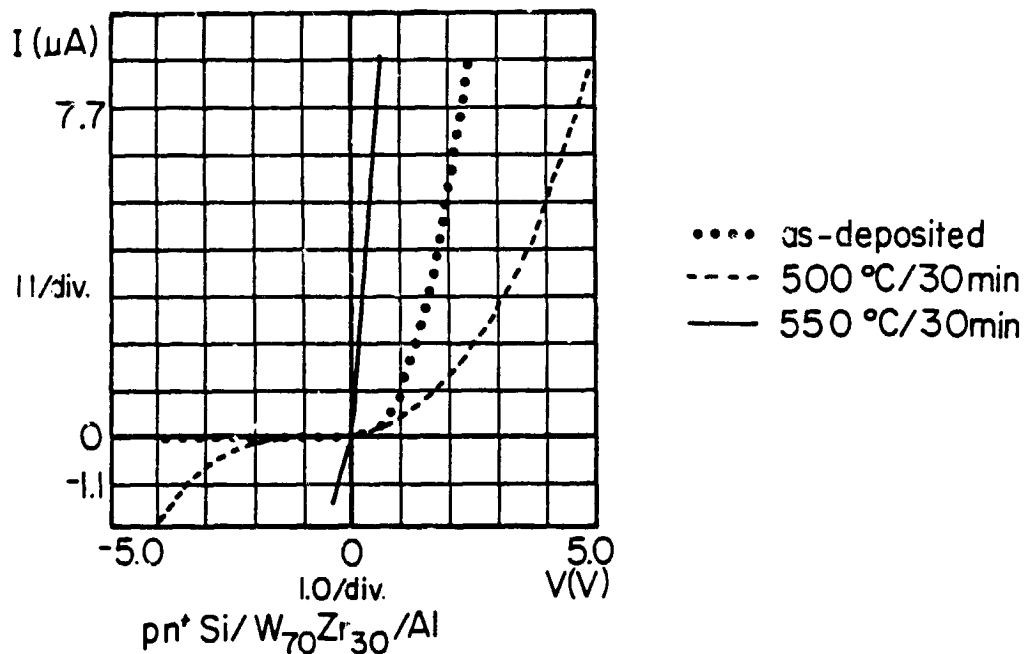
JUNCTION AREA : 500 x 500 μm^2

CONTACT AREA : 300 x 300 μm^2

As SURFACE CONCENTRATION : $5E20 \text{ cm}^{-3}$

PROCESSING

I-V Characteristic of n^+p Solar Cell with W-Zr Diffusion Barrier



Behavior of W-Zr Diffusion Barrier

1) INTERDIFFUSION IN [Si] / W-Zr / Al SETS IN

AT ~ 500°C DESPITE T_c IS AS HIGH AS 900°C

(Al+W 500°C

Al+Zr 400°C)

2) REACTION BETWEEN AL AND Zr-W IS LATERALLY

NONUNIFORM ---PITS FORMATION

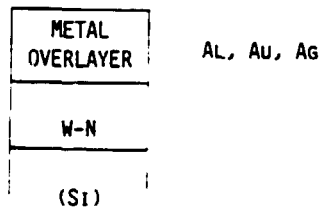
** W-Zr CANNOT BE USED AS SACRIFICIAL BARRIER

** W-Zr EFFECTIVE BELOW 500°C

PROCESSING

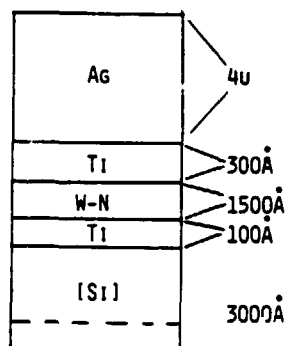
W-N Barriers

PREVIOUS WORK:

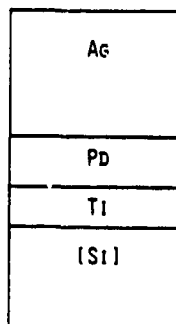


- W-N INHIBITS INTERDIFFUSION BETWEEN METAL OVERLAYER AND Si UP TO:
 - 550°C - 30 MIN. FOR AL
 - 800°C - 30 MIN. FOR Au
 - 700°C - 30 MIN. FOR Ag

Experimental: Solar Cell with W-N Diffusion Barrier



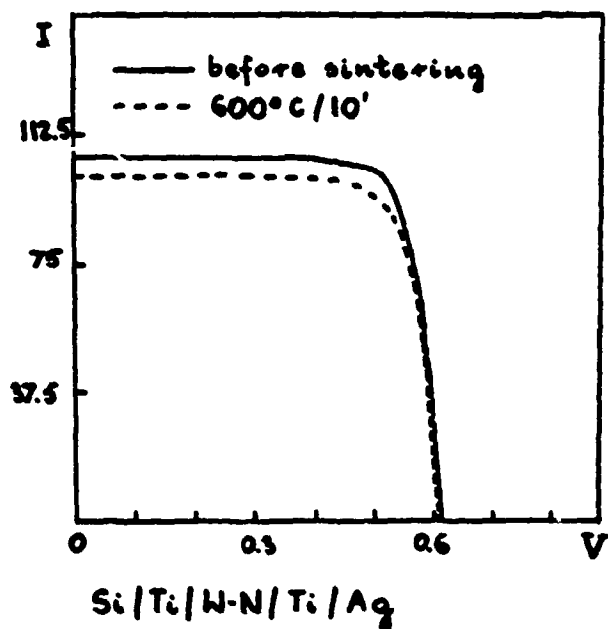
Experimental: Solar Cell with Ti-Pd-Ag Metallization



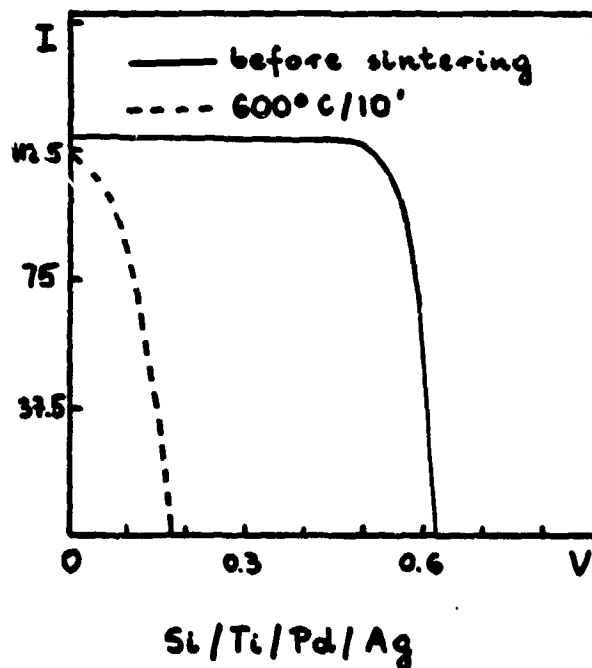
- ANNEALED IN FORMING GAS AT 400°C, 600°C FOR 10 MIN.
- I-V MEASURED UNDER AMO ILLUMINATION AT R.T.

PROCESSING

I-V Characteristic of n^+p Solar Cell with W-N Diffusion Barrier Under AMO Illumination at Room Temperature

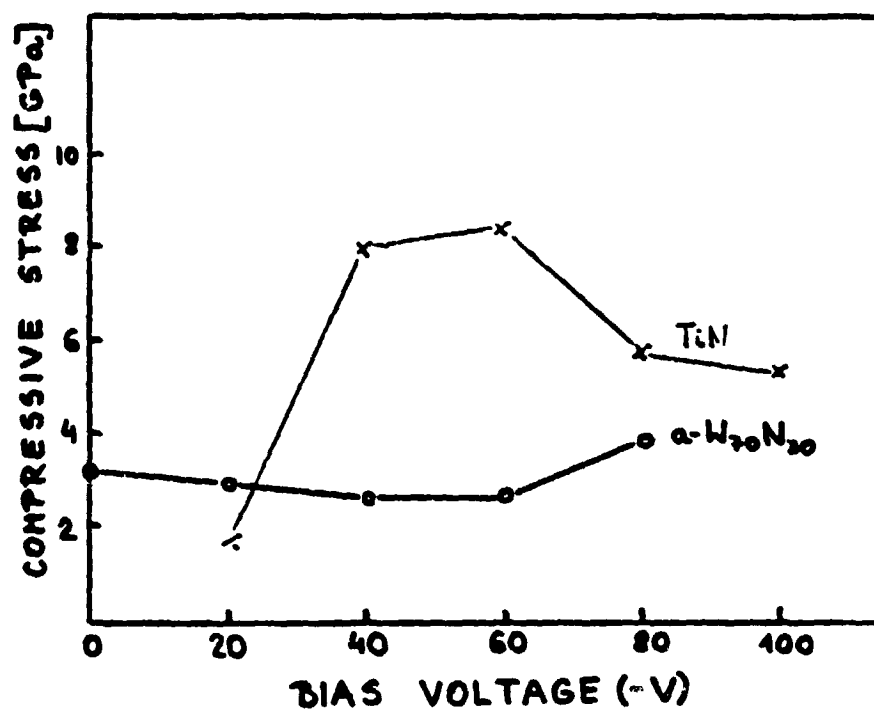


I-V Characteristic of n^+p Solar Cell with Ti-Pd-Ag Metallization



PROCESSING

Comparison Between Intrinsic Stress Properties of Magnetron-Sputtered TiN and α -W-N Films



Conclusions

- 1) W-Zr, Ni-W, Ni-Mo
 - FAILURE MECHANISM - REACTION WITH METAL OVERLAYER BELOW T_c
 - NEED TO FIND WAYS TO SUPPRESS THIS REACTION (E.G. NiNW)
- 2) WN
 - EFFECTIVE BARRIER BETWEEN $\left. \begin{matrix} \text{AL} \\ \text{Ag} \\ \text{Au} \end{matrix} \right\}$ AND Si UP TO $\left\{ \begin{matrix} 550^\circ\text{C}/30' \\ 700^\circ\text{C}/30' \\ 800^\circ\text{C}/30' \end{matrix} \right.$
 - STABLE Si/Ti/WN/Ag CONTACT TO SOLAR CELLS UP TO $600^\circ\text{C}/10'$
 - LOWER STRESS W-N FILMS CAN BE PRODUCED BY APPLYING NEGATIVE SUBSTRATE BIAS VOLTAGE